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10/29/01

U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10032930	10/29/2001	257/428	622	2814	D. LE

**APPLICANTS: Min Heikyung; Kurihara Steven; Spence Bob;

257 758

**CONTINUING DATA VERIFIED: N/A DL

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** FOREIGN APPLICATIONS VERIFIED: N/A DLPG-PUB DO NOT PUBLISH ☒RESCIND ☐

Foreign priority claimed

☐ yes ☒ no

35 USC 119 conditions met

☐ yes ☒ no

Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

072219-0278259 (P05108)

TITLE : Apparatus and method for reducing surface zener drift using Ti-based metallurgy

U.S. DEPT. OF COMM./PAT. & TM-PTO-436L (Rev. 12-94)

~~Semiconductor structure for reducing surface~~
~~zener drift using titanium-based metallurgy~~

NOTICE F ALLOWANCE MAILED

11/23/04

Assistant Examiner

CLAIMS ALLOWED

Total Claims

15

Print Claim for
O.G.

1